

IN THE CLAIMS

Claim 16 has been amended as follows:

1	16. (Amended) A semiconductor device having a semiconductor chip,
2	first electrodes formed on said semiconductor chip,
3	barrier metals formed on said first electrodes and having laminated structures, and
4	a plurality of second protruded electrodes, which serve as external connection terminals,
5	formed on said barrier metals, wherein said barrier metals comprising:
6	a lowermost conductive metal layer laminated on said first electrodes, said lowermost
7	conductive metal layer having a joining property with said first electrodes;
8	an intermediate conductive metal layer laminated on said lowermost conductive metal
9	layer, said intermediate conductive metal layer comprising one or more layers and having a joining
10	property with said lowermost conductive metal layer, said intermediate conductive metal layer
11	having at least one layer serving as a barrier layer for preventing said protruded electrodes from
12	diffusing into said intermediate conductive metal layer being made of nickel (Ni); and
13	an uppermost conductive metal layer laminated on said one or more intermediate
14	conductive metal layers, said uppermost conductive metal layer being made of a material which
15	easily alloys with the material of said intermediate conductive metal layers and which has resistance
16	to oxidation, wherein said uppermost conductive metal layer is being made of a metal selected from

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- the group consisting of gold (Au), platinum (Pt), palladium (Pd), silver (Ag) and rhodium (Rh) or
- of an alloy containing a metal selected from the group consisting of gold (Au), platinum (Pt),
- palladium (Pd), silver (Ag) and rhodium (Rh).